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	REVISION		
LETTER	DESCRIPTION	DATE	APPROVED
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IMPORTANT NOTICE

This specification contains important precautions, handling, and storage instructions and must accompany the packaged wafers or chips at all times.

Failure to follow the instructions may void the warranty.

			Title		
Centrol Semiconductor Corp. 145 Adams Avenue, Hauppauge, NY 11788 USA Tel: (631) 435-1110 • Fax: (631) 435-1824 w w w . c e n t r a l s e m i . c o m			WAFER / CHIP STORAGE AND HANDLING		
Originator	Engineering	Quality	Operations	Marketing	Management
JEF	JS	CG	JS for JR	SR	JS for JR
Date 7/24/02	Date 8-12-02 Size A	Date 8-12-02 Sheet 1 of 2	Date 8-13-02 Drawing CPS	Date 8-13-02 Number 170	Date 8-13-02 Rev. B

- 1.0 Purpose: This specification defines the requirements for proper storage and handling of Central Semiconductor Corp. wafers and chips.
- 2.0 Wafer and chip storage:
 - 2.1 Wafers and chips are to remain in the carriers provided by Central Semiconductor Corp. until ready to use.
 - 2.2 Wafers and chips are to be stored as follows:
 - 2.2.1 For short term storage (less than 1 month) and during handling and processing, wafers and chips should be kept in an environment with a Relative Humidity level controlled between 35% and 65% to prevent damage due to Electro-Static Discharge (ESD).
 - 2.2.2 For long term storage (more than 1 moth) wafers and chips should be kept in an inert gas, dry air, dry nitrogen, or in nitrogen flow boxes. The Relative Humidity level must be controlled between 7% and 30% and the environment must be free from moisture and contaminants.
 - 2.2.3 Wafers and chips are to be stored between 18°C and 24°C. For transport (less than 5 days) wafers and chips may be stored between 8°C and 60°C.
- 3.0 Wafer handling:
 - 3.1 Always wear static dissipative garments while handling wafers.
 - 3.1.1 Conductive wrist straps or ground straps.
 - 3.1.2 Static dissipative cleanroom gloves.
 - 3.2 Always handle wafers by the edges only.
 - 3.2.1 Wafer tweezers or vacuum wands should be used to move wafers from the carrier, or anytime it is necessary to touch the actual wafer.
 - 3.3 Always make sure that any surface to come in contact with the wafer is grounded, clean, and free from any objects that could cause potential damage.
 - 3.4 It is recommended that all wafer processing (such as unpacking, inspection, sawing, die bonding, wire bonding) be performed in an at least class 10,000 (ISO 7) clean room environment.

4.0 Chip handling:

- 4.1 Always open chip trays in an environment free from static build up.
 - 4.1.1 Use an ionizer to remove static build up in the surrounding air and all surrounding surfaces.
 - 4.1.2 Wear grounding straps and static dissipative garments to prevent static build up on the body.
 - 4.1.3 Place the chip tray on a static dissipative surface before opening.

4.2 Always take extreme caution when opening chip trays.

- 4.2.1 Carefully remove the tray clip. Insure that the tray cover is held tightly in place during removal of the chip tray clip.
- 4.2.2 Gently lift the tray cover up and off of the chip carrier tray. The polyethylene insert must remain on the chip carrier tray.
- 4.2.3 Slowly **slide** the polyethylene insert off the chip carrier tray in a horizontal motion.
- 4.3 Always use a vacuum pencil with a non-abrasive tip or equivalent for the removal and handling of individual die.
- 4.4 It is recommended that all chip processing (such as unpacking, inspection, die bonding, wire bonding) be performed in an at least class 10,000 (ISO 7) clean room environment.

